MD.26.

Title	**The deposition process of ZnO films doped with Eu and functionalized with Pd**
Authors	Lupan Cristian; Trofim Viorel.
Institution	**Technical University of Moldova**
Patent no.	Patent application entry number 1974, 2019
Description EN	The invention relates to the technology for deposition of semiconductor oxide films, in particular to the process of obtaining of $ZnO:Eu^{3+}$ films, with application of rapid thermal annealing (T=650 °C, t=60s), with can be applied to the manufacture of gas sensors obtaining sensibility $S=I_{gas}/I_{air}=1.3$ for 100 ppm H_2 gas at room temperature and $S=I_{gas}/I_{air}=118$ at operating temperature of 250 ºC.
Class no.	12. Safety, protection and rescue of people